

1762

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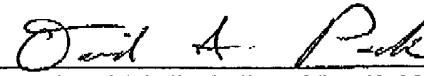
Applicant(s):	Woo Sik Yoo	OFFICIAL	
Assignee:	WaferMasters, Inc.		
Title:	METHOD OF FORMING AN OXIDE LAYER (As Amended)		
Serial No.:	10/085,498	Filing Date:	February 26, 2002
Examiner:	Jolley, Kirsten	Group Art Unit:	1762
Docket No.:	M-11549 US	Confirmation No.	8701

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Dated: July 7, 2004


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